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WHAT IS CLAIMED IS:

- 1. A process for producing a display comprising the steps of:

 forming a crystalline semiconductor film by a process comprising:
- a semiconductor film deposition process in which a semiconductor film is deposited on a substrate,

a first annealing process in which said semiconductor film is crystallized by repeatedly performing a process that melt crystallizes a portion of said semiconductor film, and

a second annealing process in which rapid thermal annealing is performed on said crystallized semiconductor film,

wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

 $1.72 \times 10^{-21} \sec < t \cdot \exp(-\epsilon/kT) < 4.63 \times 10^{-14} \sec$ wherein $\epsilon = 3.01$ eV and $k = 8.617 \times 10^{-5}$ eV/K; and forming a panel equipped with a device using the semiconductor film.

2. A process for producing a display according to claim 1, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

$$5 \times 10^{-18} \sec < t \cdot \exp(-\epsilon/kT) < 4.63 \times 10^{-14} \sec$$

wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$.

3. A process for producing a display according to claim 1, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

$$1.72 \times 10^{-21} \text{ sec} < t \cdot \exp(-\epsilon/kT) < 1.09 \times 10^{-15} \text{ sec}$$

wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$.

4. A process for producing a display according to claim 1, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

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 $5 \times 10^{-18} \sec < t \cdot \exp(-\epsilon/kT) < 1.09 \times 10^{-15} \sec$ wherein $\epsilon = 3.01$ eV and $k = 8.617 \times 10^{-5}$ eV/K.

- 5. A process for producing a display according to claim 3, wherein said substrate is glass and said annealing temperature T is below a strain point of said glass substrate.
- 6. A process for producing a display according to claim 1, wherein said annealing time t is 300 seconds.
- 7. A process for producing a display according to claim 1, wherein said annealing time t is 180 seconds or less.
- 8. A process for producing an electronic device comprising the steps of: forming a crystalline semiconductor film by a process comprising:

a semiconductor film deposition process in which a semiconductor film is deposited on a substrate,

a first annealing process in which said semiconductor film is crystallized by repeatedly performing a process that melt crystallizes a portion of said semiconductor film, and

a second annealing process in which rapid thermal annealing is performed on said crystallized semiconductor film,

wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

$$1.72 \times 10^{-21} \text{ sec} < t \cdot \exp(-\epsilon/kT) < 4.63 \times 10^{-14} \text{ sec}$$

wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$;

forming a panel equipped with a device using the semiconductor film; and

installing the panel in a body of an electronic device.

9. A process for producing an electronic device according to claim 8, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

$$5 \times 10^{-18} \sec < t \cdot \exp(-\epsilon/kT) < 4.63 \times 10^{-14} \sec$$

wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$.

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10. A process for producing an electronic device according to claim 8, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

 $1.72 \times 10^{-21} \text{ sec} < t \cdot \exp(-\epsilon/kT) < 1.09 \times 10^{-15} \text{ sec}$ wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$.

11. A process for producing an electronic device according to claim 8, wherein an annealing temperature in the second annealing process is expressed by the absolute temperature T and, when the annealing time is t, expressed in seconds, annealing temperature T and annealing time t satisfy the relationship:

 $5 \times 10^{-18} \sec < t \cdot \exp(-\epsilon/kT) < 1.09 \times 10^{-15} \sec$ wherein $\epsilon = 3.01 \text{ eV}$ and $k = 8.617 \times 10^{-5} \text{ eV/K}$.

- 12. A process for producing an electronic device according to claim 10, wherein said substrate is glass and said annealing temperature T is below a strain point of said glass substrate.
- 13. A process for producing an electronic device according to claim 8, wherein said annealing time t is 300 seconds.
- 14. A process for producing an electronic device according to claim 8, wherein said annealing time t is 180 seconds or less.